

Title (en)

DEVICE FOR WET CLEANING DISC-SHAPED SUBSTRATES

Title (de)

VORRICHTUNG ZUM NASSREINIGEN VON SCHEIBENFÖRMIGEN SUBSTRATEN

Title (fr)

DISPOSITIF DE NETTOYAGE PAR VOIE HUMIDE DE SUBSTRATS EN FORME DE DISQUE

Publication

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Application

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Abstract (en)

[origin: WO02091435A2] The invention relates to a device for wet cleaning disc-shaped substrates, especially semiconductor wafers, with the purpose of enabling continuous cleaning of individual wafers in a simple and economical manner. Said device comprises at least one processing container (40) that can be filled with processing liquid and that has a lateral guide (50) for receiving an individual substrate (2) in the container (40); a lifting device (55) in the processing container (40) for introducing and withdrawing a substrate (2), in addition to a receiving device (36) arranged above the processing container, which comprises at least two separate guide devices (92, 93) for receiving a substrate (2), wherein the guide devices (92, 93) can be moved in such a way that they can be oriented with the guide (50) in the processing container (40).

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